

MNC 2013 (November 5-8, Royton Sapporo, Hokkaido, Japan) Schedule

Tuesday, November 5

Room E (2F)
13:30-16:40 MNC 2013 Technical Seminar in Japanese
Room F (2F)
17:00-19:00 Get Together Party

Technical Seminar in Japanese Registration Desk
November 5, 12:50 - 16:00 (2F Lobby)

Conference Registration Desk
November 5, 16:30 - 18:30 (2F Lobby)
November 6, 8:30 - 18:00 (3F Lobby)
November 7, 8:30 - 19:00 (3F Lobby)
November 8, 8:30 - 16:00 (3F Lobby)

Wednesday, November 6

Room A (Royton Hall A, 3F)			
6P-1: Opening Session 9:30-12:10 Opening Remark and 2012 Award Presentation Jack J.H. Chen, TSMC, Taiwan Tetsuo Endoh, Tohoku Univ., Japan H.-S. Philip Wong, Stanford Univ., USA			
Lunch			
Room A (Royton Hall A, 3F)	Room B (Royton Hall D, 3F)	Room C (Emerald Room A, 3F)	Room D (Emerald Room B, 3F)
6A-2: 13:30-15:00 Nanoimprint, Nanoprint and Rising Lithography I	6B-2: 13:30-15:20 Functional Nanodevices	6C-2: 13:30-15:00 Nano-Tool 6C-2 Author's Interview: 15:00-15:10	6D-2: 13:30-15:30 Advanced Photolithography 6D-2 Author's Interview: 15:30-15:40
Lobby (3F in front of Royton Hall)			
Coffee Break			
6A-3: 15:15-16:55 Nanoimprint, Nanoprint and Rising Lithography II	6B-3: 15:35-16:55 Nanoscale Memory	6C-3: 15:25-16:55 Electron and Ion Beam Technologies	6D-3: 15:55-17:25 Nanofabrication I
6A-2,3 Author's Interview: 16:55-17:05	6B-2, 3 Author's Interview: 16:55-17:05	6C-3 Author's Interview: 16:55-17:05	6D-3 Author's Interview: 17:25-17:35
Lobby (3F in front of Royton Hall)			
17:30-19:00 Happy Hour			

Thursday, November 7

Room A (Royton Hall A, 3F)	Room B (Royton Hall D, 3F)	Room C (Emerald Room A, 3F)	Room D (Emerald Room B, 3F)
7A-4: 9:00-10:30 Symposium A: Directed Self-Assembly I	7B-4: 9:00-11:00 Nanostructure Engineered Devices 7B-4 Author's Interview: 11:00-11:10	7C-4: 9:00-10:30 Graphene	7D-4: 9:00-10:30 Inorganic Nanomaterials I 7D-4 Author's Interview: 10:30-10:40
Lobby (3F in front of Royton Hall)			
Coffee Break			
7A-5: 10:45-12:15 Symposium A: Directed Self-Assembly II	7B-5: 11:25-12:25 BioMEMS: Biochip	7C-5: 10:45-12:05 Nanocarbon Application	7D-5: 10:55-12:35 Nanofabrication II
7A-4, 5 Author's Interview: 12:15-12:25	7B-5 Author's Interview: 12:25-12:35	7C-4, 5 Author's Interview: 12:05-12:15	7D-5 Author's Interview: 12:35-12:45
Lunch			
7A-6: 14:00-15:50 Resist and Directed Self-Assembly	7B-6: 14:00-15:50 BioMEMS: Cell and Membrane	7C-6: 13:40-16:00 Organic Nanomaterials	7D-6: 14:00-15:50 Nanofabrication III
7A-6 Author's Interview: 15:50-16:00	7B-6 Author's Interview: 15:50-16:00	7C-6 Author's Interview: 16:00-16:10	7D-6 Author's Interview: 15:50-16:00
Lobby (3F in front of Royton Hall)			
Coffee Break			
Room P (Royton Hall B and C, 3F)			
7P-7: 16:20-18:20 Poster Session I Resist and Directed Self-Assembly, Nanocarbons, Nanodevices, Nanofabrication, Inorganic Nanomaterials, Organic Nanomaterials, NanoTool, Nanoimprint, Nanoprint and Rising Lithography and BioMEMS, Lab on a Chip			
Room A (Royton Hall A, 3F)			
18:30-20:30 Banquet			

Friday, November 8

Room A (Royton Hall A, 3F)	Room B (Royton Hall D, 3F)	Room C (Emerald Room A, 3F)	Room D (Emerald Room B, 3F)
8A-8: 9:00-10:30 Symposium B: Directed Nanostructure Science I	8B-8: 9:00-10:30 Advanced Microdevices I	8C-8: 9:00-10:20 BioMEMS: Microfluidics 8C-8 Author's Interview: 10:20-10:30	8D-8: 9:00-10:20 Inorganic Nanomaterials II
Lobby (3F in front of Royton Hall)			
Coffee Break			
Room A (Royton Hall A, 3F)	Room B (Royton Hall D, 3F)	Room C (Emerald Room A, 3F)	Room D (Emerald Room B, 3F)
8A-9: 10:45-11:45 Symposium B: Directed Nanostructure Science II	8B-9: 10:45-11:45 Process and Characterization	8C-9: 10:45-11:55 Nanocarbon Property I	8D-9: 10:35-11:55 Inorganic Nanomaterials III
8A-8, 9 Author's Interview: 11:45-11:55	8B-8,9 Author's Interview: 11:45-11:55	8C-9 Author's Interview: 11:55-12:05	8D-8, 9 Author's Interview: 11:55-12:05
Lunch			
8B-10: 13:00-14:30 Symposium B: Directed Nanostructure Science III	8B-10: 13:10-14:30 Advanced Microdevices II	8C-10: 13:10-14:30 Nanocarbon Property II	8D-10: 13:10-14:30 Inorganic Nanomaterials VI
8B-10 Author's Interview: 14:30-14:40	8B-10 Author's Interview: 14:30-14:40	8C-10 Author's Interview: 14:30-14:40	8D-10 Author's Interview: 14:30-14:40
Room P (Royton Hall B and C, 3F)			
8P-11: 14:40-16:40 Poster Session II Advanced Photolithography, Electron and Ion Beam Technologies, Nanocarbons, Nanodevices, Nanofabrication, Inorganic Nanomaterials, Nanoimprint, Nanoprint and Rising Lithography, BioMEMS, Lab on a Chip and Microsystem Technology and MEMS			